

Filed Via Express Mail
Rec. No.: 803227458240
On: SEPTEMBER 8, 2003
By: BSB
Brendy Belony

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Attorney Docket No.: NECF 17.638A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Mami MIYASAKA

Serial No.:

Filed:

Title: **ELECTRON BEAM EXPOSURE MASK, ELECTRON BEAM EXPOSURE METHOD, METHOD OF FABRICATING SEMICONDUCTOR, AND ELECTRON BEAM EXPOSURE APPARATUS**

Examiner:

Group Art Unit:

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

S I R :

Prior to examination on the merits and prior to calculation of the filing fee, please amend the above-captioned application as follows: